

Hourly Use Rates for the Material Research Laboratory Facilities

Rates for researchers employed by the University of Illinois at Urbana-Champaign, other public sector employers, and companies located in the EnterpriseWorks Incubator at the University of Illinois Research Park.

If you have any questions, please contact the MRL Business Office at 217-333-1372.

Rates valid from January 1, 2017 and are subject to change.

The rates listed below do not include overhead fees, such as Facilities and Administration, which will be added depending on your funding instrument or agreement.

| Laser and Spectroscopy Facility | | | |
|--|---|------------------|-----------------------------------|
| Instrument | Technique | Self Use (\$/hr) | Staff Assisted & Training (\$/hr) |
| Agilent CARY 5000 | Spectrophotometry | \$15 | \$45 |
| Black I-90 Laser | Laser | \$15 | \$45 |
| Custom Experiment | Custom Laser Experiment | \$15 | \$45 |
| Gaertner Ellipsometer | Ellipsometry | \$15 | \$45 |
| Inverted Materials Microscope | Optical Microscope | \$15 | \$45 |
| Lightwave Nd-YAG Laser | Laser | \$15 | \$45 |
| Low Temperature PL | Low Temperature PL | \$15 | \$45 |
| Mid-IR Twin OPA Laser Source | Laser | \$15 | \$45 |
| Nanophoton Raman 11 | Raman Spectroscopy | \$15 | \$45 |
| Neaspec IR AFM | Tip Enhanced Infrared Spectroscopy | \$15 | \$45 |
| Newport Solar Simulator | Solar Simulator | \$15 | \$45 |
| Nicolet Nexus 670 FTIR | Fourier Transform Infrared Spectroscopy | \$15 | \$45 |
| OL 750 Spectroradiometer | Spectroradiometry | \$15 | \$45 |
| Quantronix YLF Laser | Laser | \$15 | \$45 |
| Raman Spectroscopy | Raman Spectroscopy | \$15 | \$45 |
| Rame-Hart Contact Angle | Contact Angle Measurements | \$15 | \$45 |
| Room Temperature PL | Photoluminescence | \$15 | \$45 |
| Time Resolved PL | Time Resolved PL | \$15 | \$45 |
| Tsunami Ti-Sapphire Laser | Laser | \$15 | \$45 |
| Tsunami Ti-Sapphire Laser 2 | Laser | \$15 | \$45 |
| Two Photon Microscopy | Optical Microscopy | \$15 | \$45 |
| Varian Cary5G UV-VIS-NIR | Spectrophotometry | \$15 | \$45 |
| Witec Alpha NSOM | Near Field Scanning Optical Microscopy | \$15 | \$45 |
| Woollam VAS Ellipsometer | Spectroscopic Ellipsometry | \$15 | \$45 |
| Zeiss LSM7 Confocal | Confocal Microscope | \$15 | \$45 |

| Micro & Nano-Fabrication Facility | | | |
|--|---|-------------------------|--|
| Instrument | Technique | Self Use (\$/hr) | Staff Assisted & Training (\$/hr) |
| AJA Sputter Coater | Sputter Coater | \$19 | \$49 |
| AJA Sputter Coater 2 | Sputter Coater | \$19 | \$49 |
| Atomic Layer Deposition | Atomic Layer Deposition | \$19 | \$49 |
| Atomic Layer Deposition 2 | Atomic Layer Deposition | \$19 | \$49 |
| Ball Bonder | Ball Bonder | \$19 | \$49 |
| Cleanroom | Cleanroom | \$18 | \$48 |
| CM Furnace | Furnace | \$6 | \$36 |
| Desert Cryo Probe Station | Probe Station | \$19 | \$49 |
| E-beam Evaporator 1 | Electron Beam Evaporation | \$19 | \$49 |
| E-beam Evaporator 2 | Electron Beam Evaporation | \$19 | \$49 |
| E-beam Evaporator 3 | Electron Beam Evaporation | \$19 | \$49 |
| E-beam Evaporator 4 | Electron Beam Evaporation | \$19 | \$49 |
| Harrick Plasma Cleaner | Plasma Cleaner | \$19 | \$49 |
| Hydrogen Vacuum Furnace | Furnace | \$6 | \$36 |
| Ion Mill Evaporator | Ion Mill & Thermal Evaporator | \$20 | \$50 |
| Jandel 4 Point Probe | Four point probe | \$19 | \$49 |
| Lindberg 1 Furnace - 2 inch | Furnace | \$4 | \$34 |
| Lindberg 2 Furnace - 2 inch | Furnace | \$4 | \$34 |
| March RIE | Reactive Ion Etcher for polymer samples | \$19 | \$49 |
| March RIE2 | Reactive Ion Etcher for polymer samples | \$19 | \$49 |
| Mitutoyo Microscope | Optical Microscope | \$19 | \$49 |
| Olympus Microscope | Optical Microscope | \$19 | \$49 |
| Nanomaster RIE | Reactive Ion Etcher for polymer samples | \$19 | \$49 |
| Nanoscribe 3D Printer | Laser lithography 3D printer | \$20 | \$50 |
| Oven-Air | Oven | \$4 | \$34 |
| Oven-Vacuum | Oven | \$4 | \$34 |
| PECVD | Plasma Enhanced Chemical Vapor Deposition | \$19 | \$49 |
| PECVD 2 | Plasma Enhanced Chemical Vapor Deposition | \$19 | \$49 |
| Probe Station | Probe Station | \$19 | \$49 |
| Raith e-Line | Electron Beam Lithography | \$28 | \$58 |
| RaithPrep | Cleanroom | \$18 | \$48 |
| RIE | Reactive Ion Etcher | \$19 | \$49 |
| RTA Furnace | Furnace | \$11 | \$41 |
| Suss MJB3 - Deep UV | Mask Aligner - Deep UV | \$0 | \$48 |
| Suss MJB3 - Mask Aligner | Mask Aligner | \$0 | \$48 |
| Suss MJB4 - Mask Aligner | Mask Aligner | \$0 | \$48 |
| Thermal Evaporator | Thermal Evaporation | \$19 | \$49 |
| Tube Furnace - 6 inch | Furnace | \$6 | \$36 |
| Wedge Bonder | Wedge Bonder | \$19 | \$49 |

** Deposition of gold and paladium incurs an additional charge of \$28 per every 100 nm deposited or fraction there of.

| Microscopy-Biological | | | |
|---|--|------------------|-----------------------------------|
| Instrument | Technique | Self Use (\$/hr) | Staff Assisted & Training (\$/hr) |
| Bio-BioSEM | Bio SEM Prep | N/A | \$48 |
| Bio-Embed | Embedding & Deparaffinization | N/A | \$34 |
| Bio-EMScopeVM | EM Scope Tech Time | N/A | \$40 |
| Bio-Immunogold | Immunogold Embedding & Procedure | N/A | \$36 |
| Bio-LMSect | Trim & LM Sectioning | N/A | \$48 |
| Bio-NegDevelop | Negative Development | N/A | \$50 |
| Bio-NegScan | Negative Scanning | N/A | \$35 |
| Bio-NegStain | Negative Staining & Grids | N/A | \$45 |
| Bio-OptoMicro | Optical Camera Tech Time | N/A | \$30 |
| Bio-TEMsect | Trim & TEM Sectioning | N/A | \$64 |
| Reichert Ultracut | Microtome for TEM sample preparation | \$16 | \$46 |
| Microscopy-Scanning Probe | | | |
| Instrument | Technique | Self Use (\$/hr) | Staff Assisted & Training (\$/hr) |
| Asylum AFM 1 | Atomic Force Microscopy | \$16 | \$46 |
| Asylum AFM 2 | Atomic Force Microscopy | \$16 | \$46 |
| Asylum Cypher AFM | Atomic Force Microscopy/High Resolution | \$16 | \$46 |
| Hysitron Tip | Nanoindentation | \$10 | \$40 |
| Hysitron TriboIndenter | Nanoindentation | \$16 | \$46 |
| Piuma Nanoindenter | Nanoindentation | \$16 | \$46 |
| Microscopy-Scanning Electron | | | |
| Instrument | Technique | Self Use (\$/hr) | Staff Assisted & Training (\$/hr) |
| FEI DB235 FIB | Scanning Electron/Focused Ion Beam Microscopy | \$25 | \$55 |
| HELIOS 600i FIB | Scanning Electron/Focused Ion Beam Microscopy | \$35 | \$65 |
| Hitachi S4700 SEM | Scanning Electron Microscopy/High Resolution | \$19 | \$49 |
| Hitachi S4800 SEM | Scanning Electron Microscopy/High Resolution | \$19 | \$49 |
| JEOL 6060LV SEM | Scanning Electron Microscopy/ Low Vacuum | \$16 | \$46 |
| JEOL 7000F SEM | Scanning Electron Microscopy/Analytical SEM | \$19 | \$49 |
| Microscopy-Transmission Electron | | | |
| Instrument | Technique | Self Use (\$/hr) | Staff Assisted & Training (\$/hr) |
| Hitachi 9500 | Transmission Electron Microscopy | \$27 | \$57 |
| JEOL 2010 LaB6 | Transmission Electron Microscopy | \$20 | \$50 |
| JEOL 2010F EF-FEG | (Scanning) Transmission Electron Microscopy/Analytical | \$22 | \$52 |
| JEOL 2100 Cryo TEM | Transmission Electron Microscopy | \$20 | \$50 |
| JEOL 2200FS | (Scanning) Transmission Electron Microscopy/Analytical | \$27 | \$57 |
| PicoIndenter | Nanoindentation | \$15 | \$45 |

| Physical Property Measurement | | | |
|--------------------------------------|--|------------------|-----------------------------------|
| Instrument | Technique | Self Use (\$/hr) | Staff Assisted & Training (\$/hr) |
| Malvern Zetasizer | Particle Size and Zeta Potential Measurements | \$10 | \$40 |
| Q50-TGA | Thermogravimetric Analysis | \$16 | \$46 |
| Q800-DMA | Dynamic Mechanical Analysis | \$16 | \$46 |
| Surface Analysis | | | |
| Instrument | Technique | Self Use (\$/hr) | Staff Assisted & Training (\$/hr) |
| Cameca IMS-5f SIMS | Secondary Ion Mass Spectroscopy/ Dynamic | \$18 | \$48 |
| HVE Van de Graf | Ion Accelerator/Rutherford Backscattering Spectroscopy | \$25 | \$55 |
| KRATOS AXIS XPS | X-Ray Photoelectron Spectroscopy/Imaging XPS | \$18 | \$48 |
| NEC Pelletron | Ion Accelerator/Rutherford Backscattering Spectroscopy | \$45 | \$75 |
| PEI Trift-III TOF-SIMS | Secondary Ion Mass Spectroscopy/ Time-of-Flight | \$18 | \$48 |
| PEI5400 XPS | X-Ray Photoelectron Spectroscopy | \$18 | \$48 |
| PEI660 Auger | Auger Electron Spectroscopy | \$18 | \$48 |
| X-ray Diffraction | | | |
| Instrument | Technique | Self Use (\$/hr) | Staff Assisted & Training (\$/hr) |
| Dexco Laue | X-ray Diffraction/Laue | \$14 | \$44 |
| Philips XPert 1 | X-Ray Diffraction/ High Resolution, Line Focus | \$14 | \$44 |
| Philips Xpert 2 | X-Ray Diffraction/ Point Focus | \$14 | \$44 |
| SAXS | X-Ray Diffraction | \$10 | \$40 |
| Shimadzu EDXRF | X-Ray Fluorescence | \$20 | \$50 |
| Siemens-Bruker D5000 XRD | X-Ray Diffraction/ Powder | \$13 | \$43 |
| Support Equipment | | | |
| Instrument | Technique | Self Use (\$/hr) | Staff Assisted & Training (\$/hr) |
| Allied Multiprep | TEM sample preparation | \$6 | \$36 |
| Bell Jar Evaporator | Bell Jar Evaporator | \$10 | \$40 |
| Carbon Rod Coater | SEM Carbon Coater | \$10 | \$40 |
| Carbon String Coater | SEM Carbon Coater | \$10 | \$40 |
| Dektak 3030 | Surface Profilometry | \$15 | \$45 |
| FEI Vitrobot | Cryo-plunge for TEM sample preparation | \$12 | \$42 |
| Gatan CryoPIPS | Cryo-Ion Miller for TEM sample preparation | \$10 | \$40 |
| Gatan PIPS | Ion Miller for TEM sample preparation | \$10 | \$40 |
| Leica EM UC6 Microtome | Microtome for TEM sample preparation | \$16 | \$46 |
| SEM Sputter Coater 1 | SEM Sputter Coater | \$12 | \$42 |
| SEM Sputter Coater 2 | SEM Sputter Coater | \$12 | \$42 |
| Vibratory Polisher 1 | Vibratory Polisher | \$3 | \$33 |
| Vibratory Polisher 2 | Vibratory Polisher | \$3 | \$33 |